

n.amr - series

NOTION
S Y S T E M S

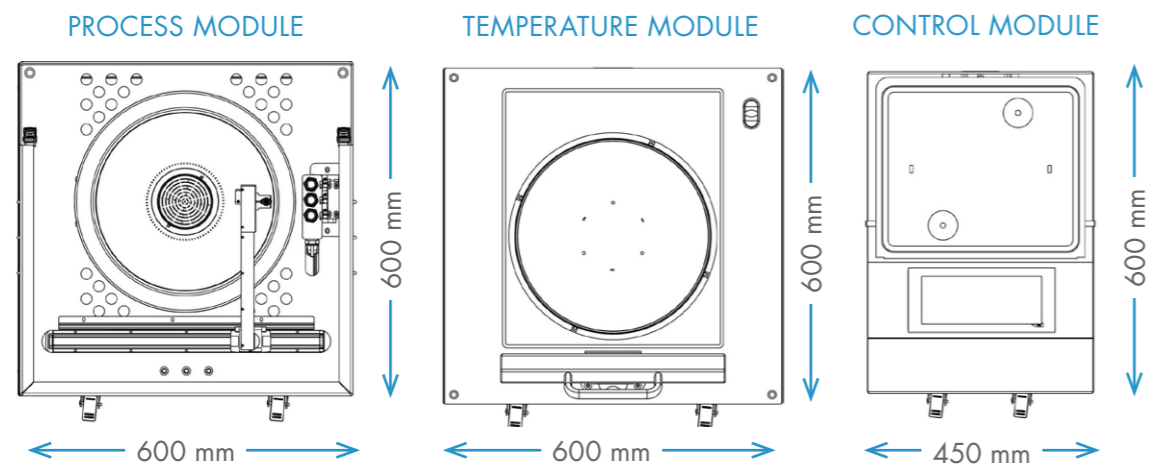
POWERED BY
amcross
systems



SEMI-AUTOMATED SINGLE WAFER PROCESSING SYSTEMS
UP TO 150 mm

FREE CHOICE FOR PROFITABLE SMALL BATCH SERIES

The modular semi-automated stand-alone spinner is the perfect device for single wafer processes for substrate sizes between 2" and 150 mm. With its very flexible fields of application in coating, lift-off, developing, cleaning, etching, vapor priming and heating it brings special benefit to R&D laboratories and other facilities with small-lot production and single process steps.

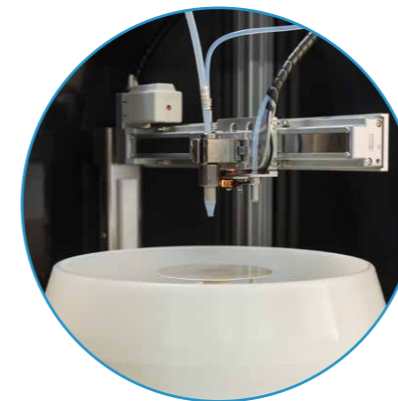


All n.amr modules have the same compact footprint (besides the control module which is even smaller). This makes the room required easily projectable and saves expensive facility/laboratory space.

BENEFICIAL HIGHLIGHTS

- Full process control: each selected process is managed by the relevant module of our comfortable amcos ams PILOT software complying with Semi-Standard E95-1101. All necessary parameters can be adjusted and will be logged into the software.
- SECS/GEM interface: the tool can be equipped with a SECS/GEM interface or other customized protocols.
- High-quality hardware: taking the same proven high-quality, standard industry-components as used for our fully automated n.amc tools powered by amcos, ensures reliability in operation, long lifetime, good serviceability and a very attractive price-performance-ratio.
- Safe: designed accordingly to the newest safety rules.

PROVEN QUALITY REQUIRING MINIMUM SPACE



Solvent module for lift-off or resist strip for standard solvents and various lift-off techniques.



Coater module with optimized bowl and exhaust for best uniformity and repeatability.



Extra-slim control module (200 x 600 mm) with touch screen on movable arm for minimum space requirements. One process module can be connected.



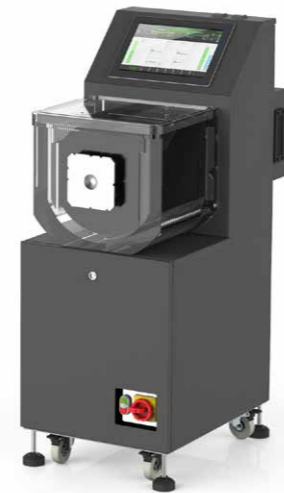
Mask cleaner

MODULAR SYSTEM FOR CUSTOMER-SPECIFIC EQUIPMENT

Our n.amr series, powered by amcross is a completely modular system. The control module, which contains the controlling system, can be combined flexibly with one or several selected processing modules (coater, cleaner, developer, lift-off, etcher, hot-/ coolplate, vapor priming hotplate, media cabinet) according to customer needs or process requirements. So, we are able to create a tool meeting the individual needs of every single client.

CONTROL MODULE

- Controlling system with ams PILOT software for the steering and easy use of the connected processing modules
- Recipes are compatible with amcross amc tools
- 12" colour touch screen with IPC
- Easy access to parts in the module's interior
- Special, slim control module available (if only one process module is required)



LIFT-OFF MODULE

- Unique lift-off process with megasonic or high-pressure
- High- or medium-pressure cleaning with DIW or solvents
- Special reclaim solution for very low media consumption
- Easy recycling of lifted metals
- Programmable wafer backside, topside and bowl rinse

DEVELOPER MODULE

- Spray-, puddle or megasonic development
- Various developer media per bowl possible
- Servo-controlled nozzle positioning programmable with absolute distance values
- Programmable wafer backside, topside and bowl rinse

COATER MODULE

- Unique bowl design for optimal process results (e.g. no cotton candy when processing high viscosity resists)
- Servo-controlled nozzle positioning, programmable with absolute distance values
- Programmable wafer backside and bowl rinse
- EBR (Edge Bead Removal) system programmable with absolute distance values, also for rectangular substrates
- Dispense system for up to 6 different media per bowl with single-nozzle positioning arm and automatic nozzle change
- Different resist dispense pumps (e.g. syringe, traptank, etc.) available



ETCHING MODULE

- Etching of a multitude of round and square wafers and masks
- Precise chemicals temperature control
- Novel chrome etchant recycling reduces use of chemicals and thus, reduces the impact on the environment and decreases processing costs

CLEANER MODULE

- Cleaning of wafer frontside, backside and edge bevel
- Various cleaning methods as standard solution available
- Suitable to work with different diluted chemicals
- Large area megasonic or megasonic nozzle

TEMPERATURE MODULE

- Standard hotplate (60 °C - 200 °C)
- High-temperature hotplate (60 °C - 450 °C)
- HMDS vapor priming hotplate (60 °C - 200 °C)
- Single or multi-zone hotplate
- Coolplate (10 °C - 60 °C), with either water or Peltier cooling
- Curing by UV light or supported by UV light
- Options for proximity control: Fixed proximity, programmable proximity, vacuum contact



MEDIA MODULE FOR WET PROCESS CHEMICALS

- Cabinet made of PP white
- Safe handling of dangerous chemicals
- Integrated exhaust connector
- Safety trip pan with leakage sensor
- Refill via chemical bottle or bulk fill
- Very small outer dimensions (250 mm width) for 2 different chemicals



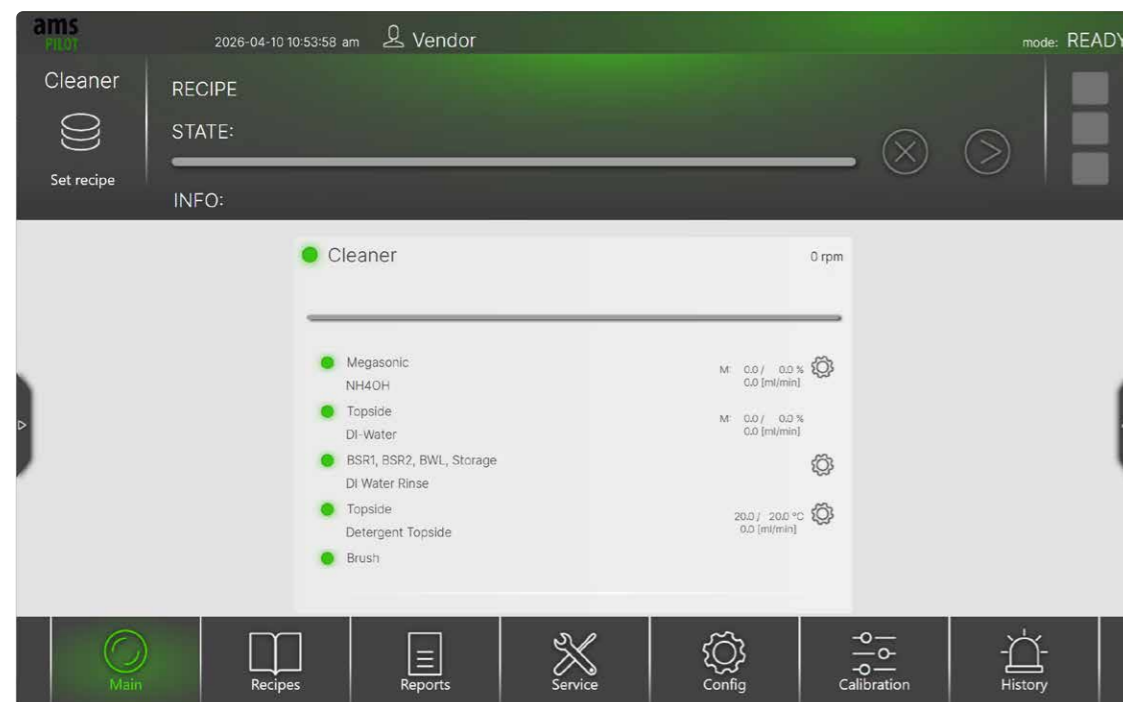
MEDIA MODULE FOR SOLVENTS


- Cabinet made of stainless steel with drawer
- Integrated exhaust connector
- Safety trip pan with leakage sensor
- Supply of different media to the system





n.ams PILOT SOFTWARE – HIGH-PRECISION PROCESS CONTROL


- Clear, well-arranged user interface with modern design: user-friendly, self-explanatory & intuitively operable
- Complies with Semi-standard E9-1101
- User interface is designed to comfortable touch operability for all users
- Unique: simultaneous right- & left-hander operability






Main



Settings


Change user


Energiesafe mode


Settings



Change user



Energiesafe mode


Supports standard SECS/GEM communication if needed.


Client-ability: the logged user will only see information relevant to him.


Power and media consumption reduction can be activated with only one click and helps to reduce energy costs.


Recipes


Reports


Alarm


Service


Calibration

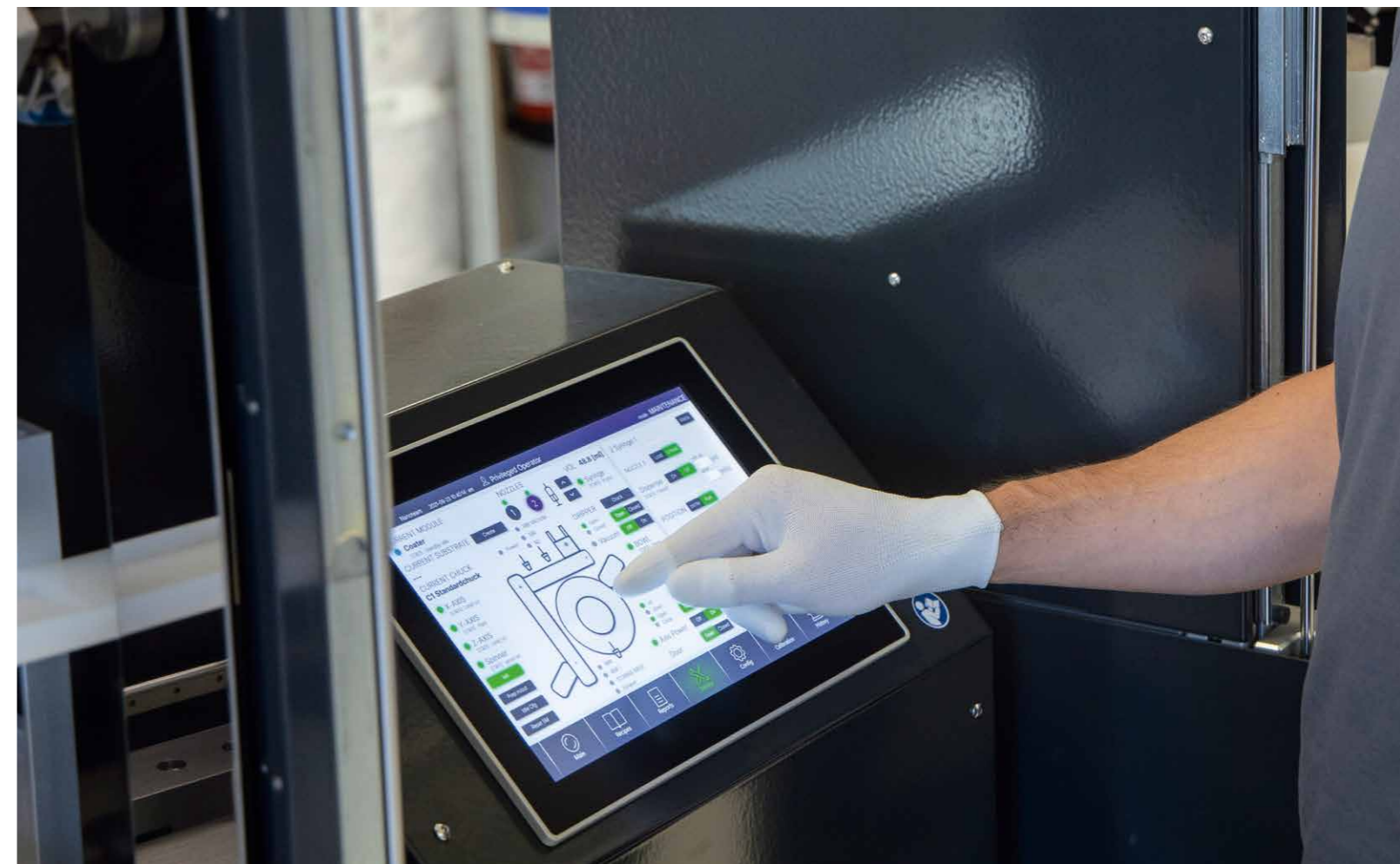
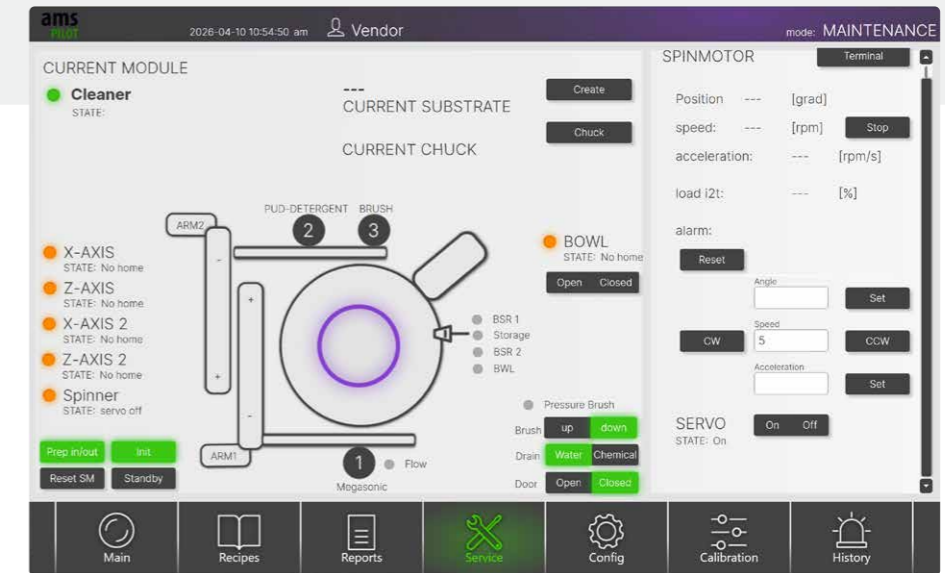
Easy recipe writing
Sequences for
accurate process flow

Alarm list & log-function for
informative reporting

Special service
and maintenance
functions

Calibration
service
functions

n.ams PILOT software independently controls processes in every equipment and therefore supports the operator and optimizes all processes.



NOTION

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